
Contents

1	Ion Beam	1
1.1	Introduction	1
1.2	Large Area Sputter Modeling	2
1.3	Focused Ion Beam	14
2	X-ray Lithography	29
2.1	Introduction	29
2.2	Mask Heating and Distortion	30
2.3	Thermal Analysis of Resist	47
2.4	Microstructure Transfer Accuracy	63
3	Laser Chemical Vapor Deposition	77
3.1	Introduction	77
3.2	Kinetically Limited Deposition	78
3.3	Mass Transport Limited Deposition	103
4	Laser Photopolymerization	123
4.1	Introduction	123
4.2	Kinetics of Photopolymerization	124
4.3	Photofabrication	140
4.4	Process Models	150
5	Laser Ablation	159
5.1	Introduction	159
5.2	Photothermal Models	160
5.3	Photochemical Models	176
5.4	Photophysical and Other Models	187
5.5	High Energy Density Laser Models	210

6 Thin Films	221
6.1 Introduction	221
6.2 Heat Transport Models at the Microscale	222
6.3 Phase-Lag Models	229
6.4 Solution Methods.....	232
6.5 Short-Pulse Laser Heating of Thin Films	238
References	249
Index	263



<http://www.springer.com/978-3-540-00252-9>

Modelling of Microfabrication Systems

Nassar, R.; Dai, W.

2003, X, 270 p., Hardcover

ISBN: 978-3-540-00252-9